

Northwestern University Micro/Nano Fabrication Facility

Exploring Inner Space

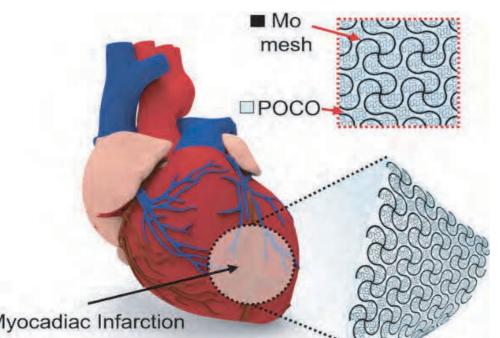
NUFAB Facility

NORTHWESTERN UNIVERSITY MICRO/NANO FABRICATION FACILITY

NUFAB is a central micro/nano fabrication facility at Northwestern University. It provides a wide range of nanofabrication equipment and technical expertise to Northwestern and other academic and industrial researchers. We support research in all areas of science, engineering, medicine, and interdisciplinary fields.

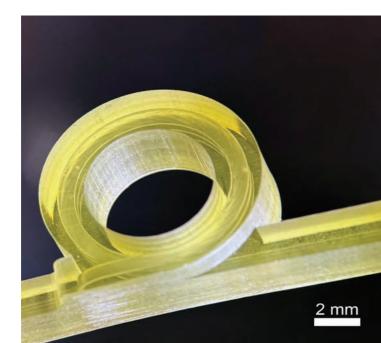
RAPID PROTOTYPING

Laser Cutter LPKF ProtoLaser R4



A bioresorbable, highly conductive, and elastic cardiac patch consists of a highly conductive bioresorbable Molybdenum mesh structure formed in an optimized filamentary serpentine geometry fabricated by LPKF Protolaser R4.

3D Printer BMF microArch D1025



Fully 3D-printed microfluidic separator with a helical channel.

Electronic Printer Fujifilm Dimatix DMP-2850

COOK CLEANROOM

- F20 Thin-Film Analyzer
- Wafer Dicing System ADT 7122
- Wire Bonder-Wedge
- AS Micro RTP System
- E-Beam Evaporator Auto 306
- E-Beam Evaporator Auto 500
- Acid Hood
- Hall Effect / Resistivity / I-V Measurements System HMS 8404

- Samco RIE 10NR
- ALD Savannah S100
- Photolithography Hood
- Mask Aligner Q4000
- Mask Aligner MABA6
- Sputter III AJA-Niobium
- Quantum Deposition **System -** Plassys
- Automatic Wire Bonder TPT HB100
- Oxide Etcher ULVAC NLD-570EXa

CHARACTERIZATION



NUFAB's Characterization Bay allows for fine measurement of physcial, electrical and optical properties of materials and devices.

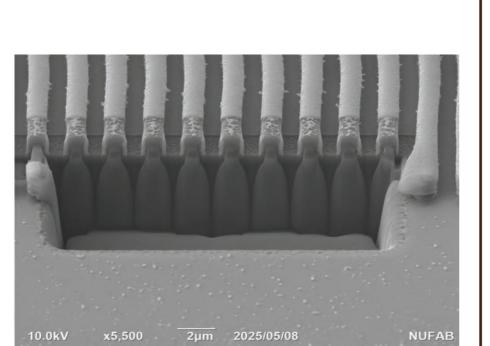
- Fluorescence/DIC Microscope Nikon LV150
- Reflectometer Filmetrics F20
- Stylus Profilometer Veeco Dektak-8
- 3D Optical Profilometer Zygo
- IV/CV Probe Station

SEM with EDS and FIB JEOLJIB-4700F

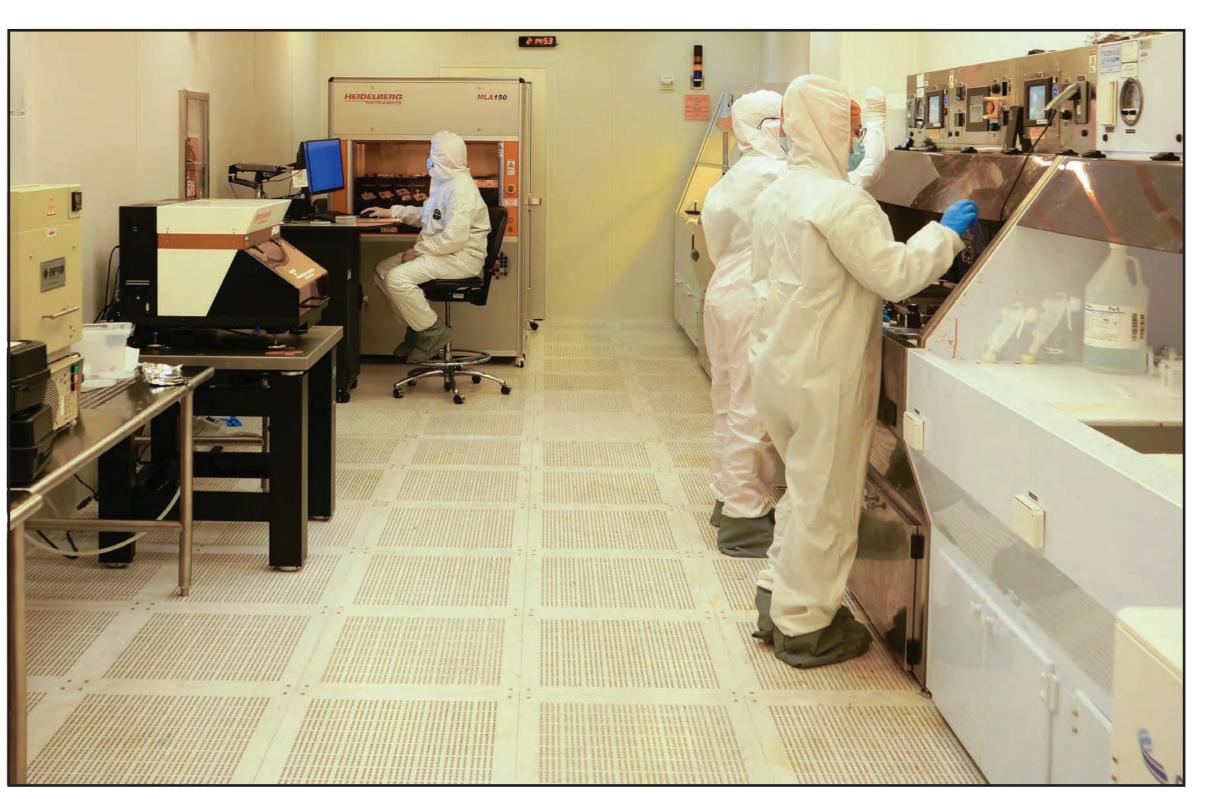
- Resolution: 1.2 nm at 15.0 kV
- Element detection range: Be(4) - Am(95)
- Gallium liquid metal ion source

Ball Bonder and Wedge Bonder

- Contact Angle Measurement VCA Optima XE Bioline Attension Theta Flow
- Thin Film Stress Measurement Toho FLX-2320S
- Ellipsometer J.A. Woollam alpha-SE



PHOTOLITHOGRAPHY



NUFAB's Photolithography Bay is configured for both mask and maskless lithography processes, including single micron scale optical lithography.

- Automatic Develop Hood Osiris UNIXX
- Ultraviolet Flood **Exposure System** Inpro Technologies F300S
- Ultrasonic & Megasonic Cleaners
- Convection Ovens Blue M DCC-146-C-ST350
- Mask Aligners Suss MABA6, Suss MJB4
- Laser Writer Heidelberg MLA150, uPG 501
- Spinner Hood
- VacuumOven (YES)

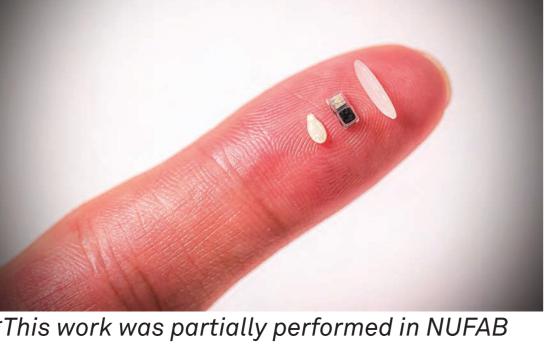
ELECTRON BEAM LITHOGRAPHY

Raith Voyager 100

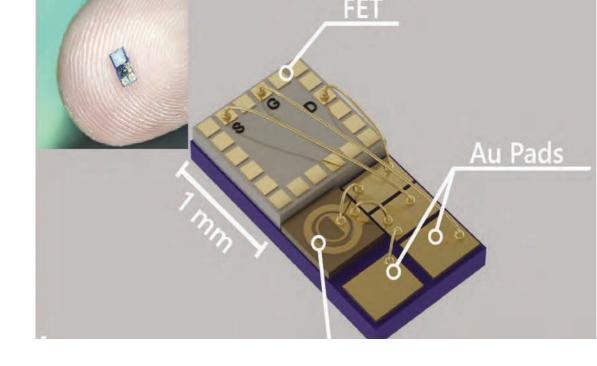
- <10 nm structures
- cm scale exposure
- High speed pattern generator
- 50 kV



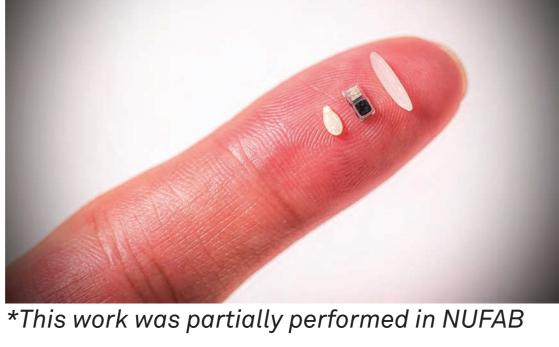
RESEARCH at NUFAB



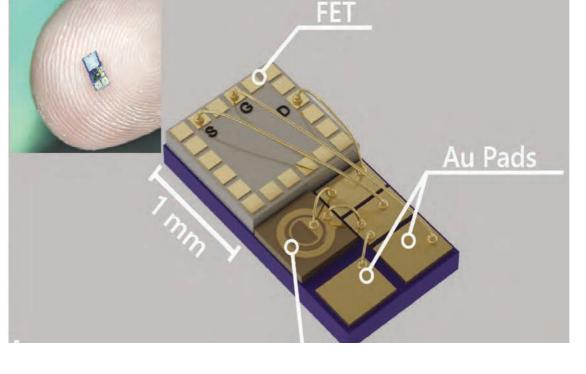
The Rogers group have developed the injected into the body, then dissolves



A 3 pJ/bit free space optical interlink platform for self-powered sensing & opto-spintronic RF-to-optical transduction



world's smallest pacemaker that is activated by light. The pacemaker is so tiny that it can fit inside the tip of a syringe and be non-invasively after it's no longer needed. - Rogers Group, Northwestern



- Mohseni Group, Northwestern

Contact Information

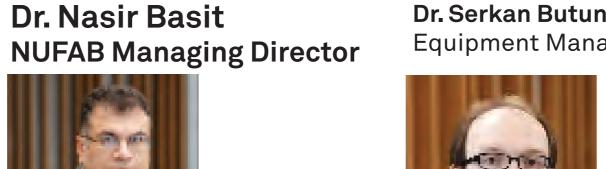
Technological Institute, FG70 NUANCE - NUFAB - Cook Cleanroom Cook Hall - Room 4026





Dr. Vinayak P. Dravid Abraham Harris Professor, Materials Science & Engineering **NUANCE** Center Founding Director











Dr. Anil Dhote





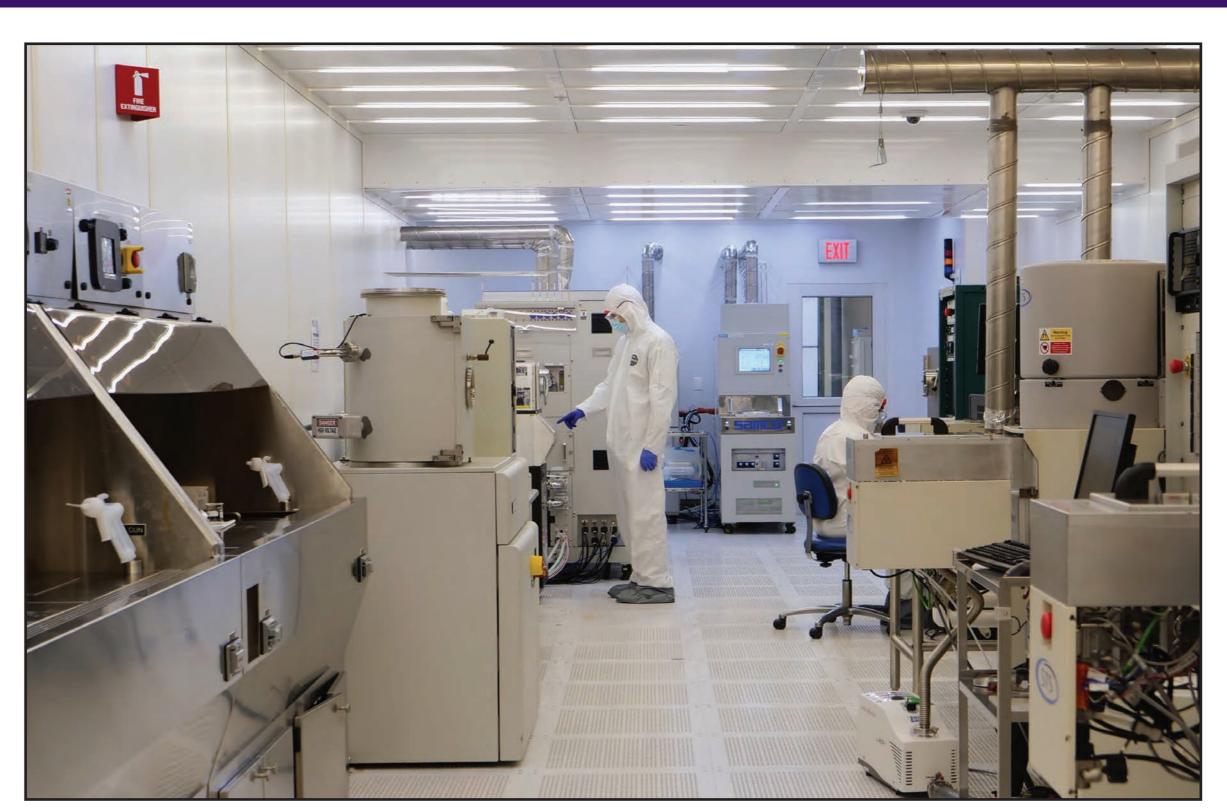






Diego Santiago De La Vega Equipment Engineer

DEPOSITION & ETCH



NUFAB's Deposition Bay is suitable for a wide variety of deposition techniques, including both PVD and CVD methods.

- Automatic Acid Etcher
- Annealing Tube Furnace Lindberg/Blue M
- Plasma Enhanced Chemical Vapor Deposition STS LpX CVD SAMCO PD-220NL
- AJA E-Beam Evaporator
- Atomic Layer Deposition Arradiance GEMStar XT-P
- Thermal Evaporator Denton Vacuum Explorer 14
- Parylene Coater SCS Labcoter2 Parylene Deposition System
- Sputters AJA Orion Sputter I & II
- Deep Reactive Ion Etcher (DRIE) STS LpX Pegasus SAMCO RIE-400iPB
- Reactive Ion Etcher (RIE) Samco RIE-10NR

Xenon Difluoride Etcher

- Xactix Rapid Thermal Processor (RTP)
- AW-610 P/N Doping Furnaces
- General purpose annealing furnace
- Tystar Low Pressure CVD
- Critical Point Dryer Tousimis Automégasamdri – 915B, Series C
- Tystar wet/dry oxidation furnace
- Plasma Cleaner SAMCO PC-300







